

**PATENT APPLICATION**  
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q93721

Hans-Juergen ROSTALSKI, et al.

Appln. No.: 10/571,267

Group Art Unit: 2873

Confirmation No.: 6099

Examiner: Darryl J. COLLINS

Filed: February 12, 2007

For: LITHOGRAPHY LENS SYSTEM AND PROJECTION EXPOSURE SYSTEM  
PROVIDED WITH AT LEAST ONE LITHOGRAPHY LENS SYSTEM OF THIS TYPE

**PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136**

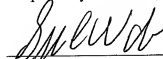
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of one month, extending the time for responding to the Office Action of July 29, 2008 to November 29, 2008. Because November 29, 2008 falls on a Saturday, this filing on Monday, December 1, 2008 is timely.

The USPTO is directed and authorized to charge the statutory fee of \$130.00 and all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account.

Respectfully submitted,



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WASHINGTON OFFICE

**23373**

CUSTOMER NUMBER

Date: December 1, 2008